

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Tetsuo SHIMOMURA, et al
App. No : 10/598,717
Filed : September 8, 2006
For : POLISHING PAD AND
SEMICONDUCTOR DEVICE
MANUFACTURING METHOD
Examiner : Alvin J Grant
Art Unit : 3723
Conf No. : 9262

AMENDMENT**Mail Stop Amendment**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action dated February 25, 2009, Applicants respectfully submit the following amendments and remarks in connection with the above-captioned application.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.